



IJRASET

International Journal For Research in
Applied Science and Engineering Technology



INTERNATIONAL JOURNAL FOR RESEARCH

IN APPLIED SCIENCE & ENGINEERING TECHNOLOGY

Volume: 8 Issue: II Month of publication: February 2020

DOI: <http://doi.org/10.22214/ijraset.2020.2027>

www.ijraset.com

Call:  08813907089

E-mail ID: ijraset@gmail.com

Preparation and Characterization of Al doped SnO₂ Nanocrystalline Thin Films by Spray Pyrolysis Technique

V. Kirthika¹, S. Porchelvi², K. Pakiyaraj³, K. Karthik⁴

^{1,2}Department of Physics, Sakthi College of Arts and Science for Women, Oddanchatram, India.

³Department of Physics, Arulmigu Palaniandavar College of Arts & Culture, Palani, India;

⁴Center for Advanced Materials, Qatar University, Qatar.

Abstract: Al-doped Tin Oxide (SnO₂) nanostructured (ATO) thin films are prepared by Spray Pyrolysis technique on glass substrates Prepared at 400°C and annealed at 500°C, 600°C. Using a solution consisting of SnCl₄·5H₂O starting material and doping source was AlCl₃ with various Al doping ratio. Sn_{1-x}Al_xO₂ (x = 0.04, 0.06 and 0.08) were dissolved in ethanol and stirred four hours at 50°C. The effect of changes in doping content and annealing effect of Al:SnO₂ nanostructured thin films was investigated. The result of X-ray diffraction has shown that peak located at around 2θ = 37.9° is corresponding to (200) plane which confirmed the presence of SnO₂ in tetragonal crystal system. All the observed characteristic peaks are well matched with the standard data base values. The UV-Visible transmittance figures are clearly depicting that all the prepared thin films are having transparency of 80%, the optical band gap was estimated to be around 2.56eV to 3.6eV. The scanning electron microscopic (FESEM) analyses show the crack-free and dense nature of the thin film formation. The size of the particle was measured from FESEM images and it was found to be in the range of 40-54nm. In AFM the average crystallite size was estimated 45nm and the root mean square roughness value was found to be 20 nm. EDAX to confirm the presence of dopant elements in the nanostructured thin films.

Keywords: Spray Pyrolysis, XRD, morphological and optical properties.

I. INTRODUCTION

The transparent conducting tin oxide (SnO₂) thin films have been widely used in many field owing to their, unique properties such as high electrical conductivity and high transmittance in the UV-Visible region [1,2]. Its properties are strongly depend on the deviation of stoichiometry, oxygen deficiency and the nature of the presence of impurity [3,4]. This material has proved itself to be one of the most attractive materials for gas sensor applications due to its special properties such as chemical and thermal stability and non-stoichiometry. Many researchers have been working to tailor the physical properties of SnO₂ thin films by employing different cationic and anionic dopant like Fluorine, Antimony, Zinc, Nickel, Aluminium etc., Depending upon the dopant, the SnO₂ thin films exhibit n-type or p-type conductivity. Aluminium is one of the acceptor impurity which acts as a lower valence cation in SnO₂ and can cause the p – type conductivity. Al doped tin oxide (ATO) nanocrystalline thin films can be prepared by a number of method such as spray pyrolysis [5], sputtering [6], CVD [7], Plasma and sol-gel methods [8-11]. Spray Pyrolysis is suitable for a variety of oxide materials and relatively inexpensive. ATO thin films have been prepared using a spray pyrolysis technique and different amount of Al doped SnO₂ thin films were prepared at T_S=400°C and annealed at 500°C, 600°C. The effect of Al doping on the structural, optical, morphological and electrical properties of SnO₂ thin films have been studied. The prepared Al doped SnO₂ thin film has been used to many applications for gas sensing device.

Tin Oxide (SnO₂) is one of the transparent conducting Oxide (TCO) material having wider band gap of 3.6 eV [12] and ionic radius is Sn⁴⁺ r = 0.71Å [13]. To our knowledge undoped SnO₂ is an n-type semiconductor due to the presence of intrinsic defects like oxygen vacancies. Recent investigations have been focused on increasing n type conductivity of this material [14, 15], while both high quality n-and p type SnO₂ are essential for fabrication of SnO₂ based semiconductor devices. SnO₂ behaves as an n-type semiconductor, However when there is a suitable dopant doped with it, the carrier conversion takes place and change to P type semiconductor [16]. A lower valency cation as acceptor impurity such as Al³⁺ (ionic radius r = 0.51Å) [13] in tin oxide decreases n type conductivity and increases the hole concentration and hence the p – conductivity. However, it is to be noted that in a successful acceptor doping process, besides doping level, effect of annealing and the atomic or cationic size of the acceptor dopant is very

important. The current investigation was done on the fully transparent conductive sprayed Al: SnO₂ nanostructure thin films. The n type SnO₂ inverted to P type conductivity prepared by SPD was evidenced [13].

In this paper, we report the effect of Al doping percentage and annealing effect of films, variation on structural, electrical and optical properties of SnO₂:Al thin films prepared by homemade Spray pyrolysis technique.

II. EXPERIMENTAL

Aluminum doped SnO₂ films were deposited onto the glass by Spray pyrolysis technique. The starting material for Sn was (SnCl₄.5H₂O) and doping source was aluminum chloride (AlCl₃). Both precursor and doping compound were dissolved in ethanol. The starting doping ratio (Al/Sn) was 4% in the solution. The resulting solution were stirred four hour at temperature 50°C, spray rate and substrate to nozzle distance were maintained respectively at 10ml/min and 25cm. The glass substrate was mounted on hot plate then heated to 400°C which was controlled by dimmastrate and digital thermometer connected to the hot plate. Then prepared samples were annealed at 500°C and 600°C by muffle furnace. After synthesizing the films, their structural, optical and electrical characterizations were performed. The structural properties of our samples were carried out by a Rigaku X-ray Diffractometer model DMAX 2200 with a copper anticathode (CuKα, λ = 1.5Å) with an angle range (2θ) of 20-70°. The optical parameters of the as – synthesized and annealed Al - SnO₂ films were measured using a shima DZU UV – 3101PC double beam spectrometer. The samples surface morphology was analyzed by the Field emission scanning electron microscope (FESEM:JEOL JSM 6701F), Atomic Force Microscopy (AFM). The elemental composition of the samples was determined by oxford instrument-INCAPENTAFET-X3 Elemental dispersive X-ray analyzer (EDAX).

III. RESULT AND DISCUSSION

A. Structural Properties

The effect of Al doping on SnO₂ has been investigated by various researchers in the past [17, 18]. With increasing Al dopant and annealing temperature in the tin oxide film, the crystalline of SnO₂ decreased. Hence the doping element Al is a grain growth inhibitor. The X-ray diffractogram of Al doped SnO₂ thin films prepared at the substrate temperature T_S= 400°C and annealed at 500°C, 600°C are shown in Figures (1a),(1b) and (1c). A peak located at around 2θ=37.9° is corresponding to (200) plane which confirmed the presence of SnO₂ in tetragonal crystal system. All the observed characteristic peaks are well matched with the standard data base values (JCPDS File No.88-0287). It can be clearly seen that the intensity of observed peaks are decreasing upon the increase of doping concentration. At the same time by comparing the XRD pattern of pure SnO₂ thin film a very small peak shift is observed in the case of Al doped SnO₂ thin films. This peak shift and the decrease in the intensity are due to the hinder of grain growth. The crystallite size was calculated using Scherrer's formula [19] and the average crystallite size found to be 32, 37,40 nm for 400°C, 500°C and 600°C respectively.

Furthermore increasing the temperature leads to higher degree of crystallization and as a result new characteristic peak corresponding to (211) is observed. There is no any peak corresponding to Aluminium oxide, which implies the substitution of Al inside the SnO₂ lattice. It was observed that the peaks base was broadened. It should confirm the nanostructures occurrence of the Al - SnO₂ sample. This was in well agreement with the FESEM and EDAX. Fig (1b) shows that Al doping content and annealing effect to reduce the grain size. and annealing effect to reduce the grain size.

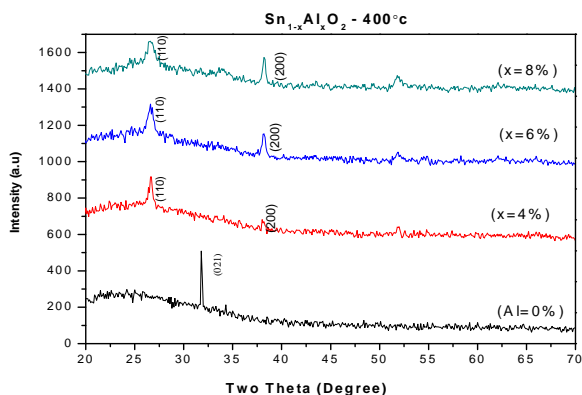


Fig. 1a XRD pattern of Al doped SnO₂ films deposited on glass substrates at 400°C

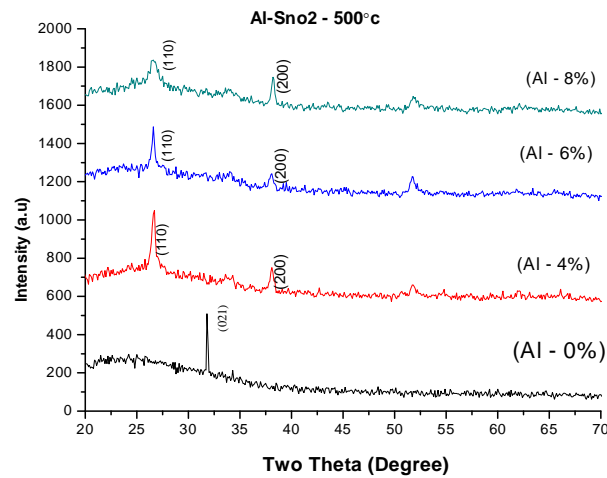


Fig. 1b XRD pattern of Al doped SnO₂ films deposited on glass substrates annealing at 500°C

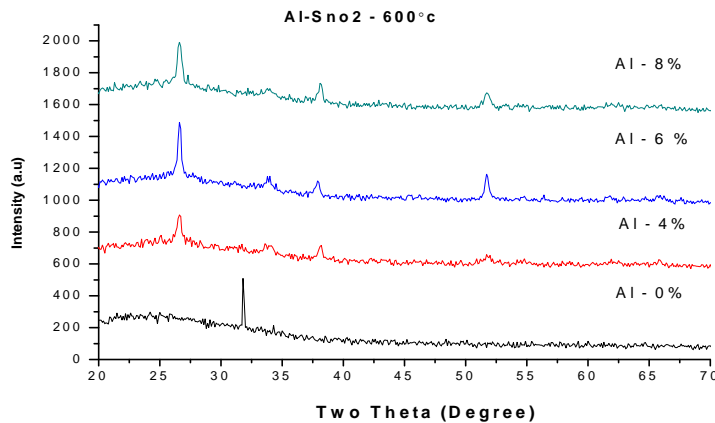


Fig. 1c XRD pattern of Al doped SnO₂ films deposited on glass substrates annealing at 600°C

B. Optical Properties

Figures (2a-c) shows the UV-Visible spectra of Al doped SnO₂ thin films prepared at the temperature of T_S = 400°C and annealed temperature at 500°C and 600°C respectively. These figures are clearly depicting that all the prepared thin films are having transparency of 80%. Thin films annealed at 500°C shows the highest transparency (Figure 2a) of 90%. Further increasing the annealing temperature leads to the decrease of transparency. This is may be due to the increase of the density of the films upon the increasing of temperature. . From the fig it is observed that the transmission of the film decreases with increase in Al concentration and annealing effect. The average percentage of transmission of all the thin film samples is lies between (25% - 85%) in visible region. The optical band gap of the deposited Al - SnO₂ thin films are calculated by using the following formula [19]

$$(\alpha h\nu) = (h\nu - E_g)^{1/2} \quad (1)$$

Where α (m⁻¹) is the absorption coefficient h (J.S) is Planck's constant ν (HZ) is the photon frequency E_g (eV) is the band gap energy. Figure (3a), (3b) and (3c) show the Tauc's plot drawn between $(\alpha h\nu)^2$ and $h\nu$ (eV). As seen from these figures, the band gap energy was found to be 4% to 8% aluminum content at deposition temperature 400°C (prepared), annealing at 500°C and annealing at 600°C. The calculated direct band gap values of Al - SnO₂ films lay in the range 3.62 eV to 2.63eV for Al doped and undoped SnO₂ respectively. Which are also comparable with the values already reported 3.604 to 4.105 eV [20], 3.87 to 4.21eV [18]. The band gap narrows down due to the decrease in the number of charge carriers with increasing in Al doping and annealing temperature.

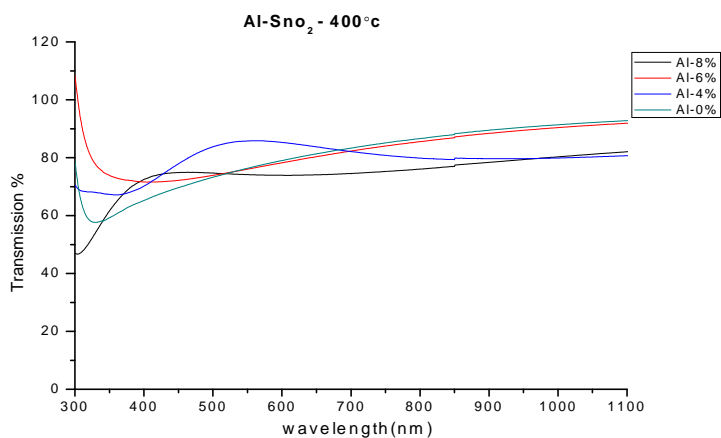


Fig. 2a Transmission spectrums of Al doped SnO₂ films deposited on glass substrates at 400°C

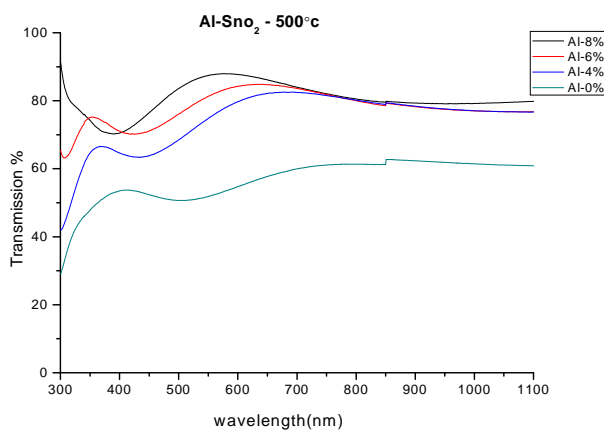


Fig. 2b Transmission spectrums of Al doped SnO₂ films deposited on glass substrates annealing at 500°C

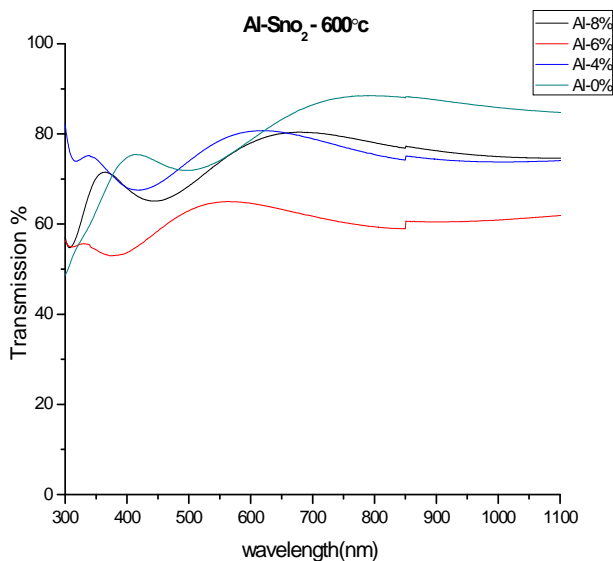


Fig. 2c Transmission spectrums of Al doped SnO₂ films deposited on glass substrates annealing at 600°C

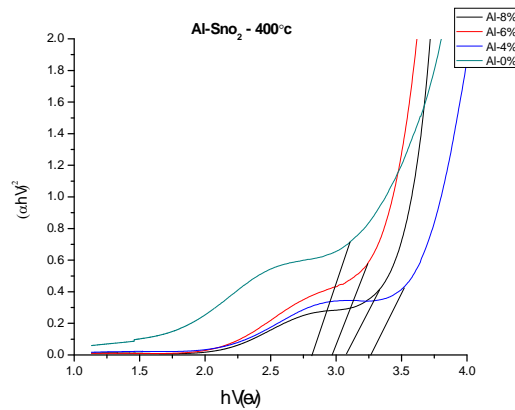


Fig. 3a Optical band gap of Al doped SnO₂ films deposited on glass substrates at 400°C

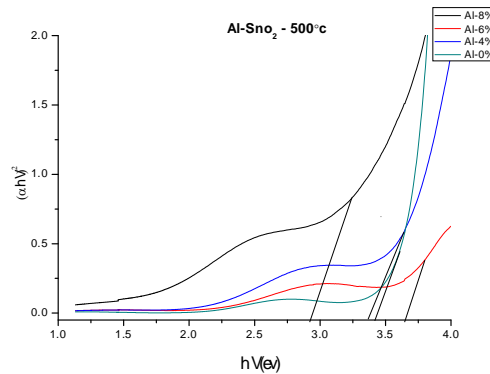


Fig. 3b Optical band gap of Al doped SnO₂ films deposited on glass substrates annealing at 500°C

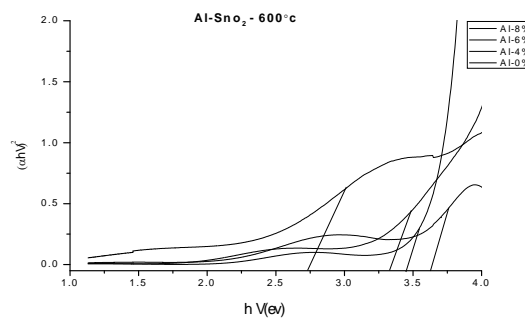


Fig. 3c Optical band gap of Al doped SnO₂ films deposited on glass substrates annealing at 600°C

C. Morphological and Elemental Studies

In order to ascertain the film nature and the morphology, the prepared thin films have been examined by FESEM analysis. Figure (4a) showing the FESEM image of Undoped SnO₂ thin films prepared at the substrate temperature of T_S=400°C, Figures (4b), (4c) and (4d) are showing the FESEM images of 4%, 6%, and 8% of Al doped SnO₂ thin films prepared at the substrate temperature of T_S=400°C and annealed temperature at 500°C and 600°C respectively. Those figures show the crack-free and dense nature of the thin film formation. But there are agglomerated particles present on the film surface. Increasing the doping concentration leads to decrease of agglomeration. In all the cases FESEM images depicted the clear and dense nature of the film surface with homogeneous distributions of spherical shaped nanoparticles. The size of the particle was measured from FESEM images and it was found to be in the range of 40-54nm. Also the increase of particle size with increased of annealing temperature caused by the grain growth.

The presence of aluminum in the SnO₂ thin films (prepared at T_s=400°C and annealed temperature at 500°C and 600°C) was confirmed by EDAX spectra Figures (5a), (5b) and (5c). All the EDAX spectra showed the Al peaks and some other peaks are also found which is due to the substrate. The peaks show the element that has been detected from the sample confirming the presence of Al, Sn and Oxygen in Al - SnO₂ thin films.

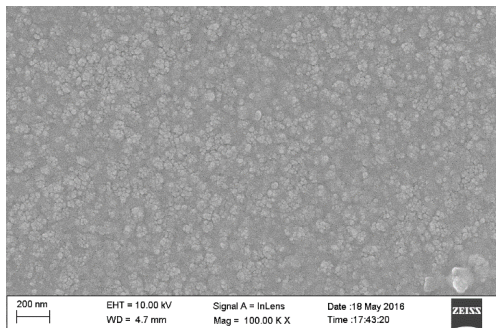


Fig. 4a FESEM of undoped SnO₂ films deposited on glass substrates at 400°C

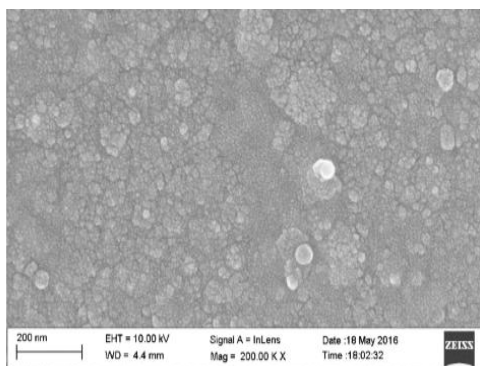


Fig. 4b FESEM of Al doped SnO₂ films deposited on glass substrates at 400°C

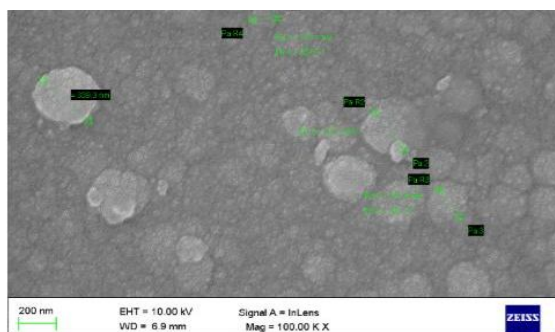


Fig. 4c FESEM of Al doped SnO₂ films deposited on glass substrates annealing at 500°C

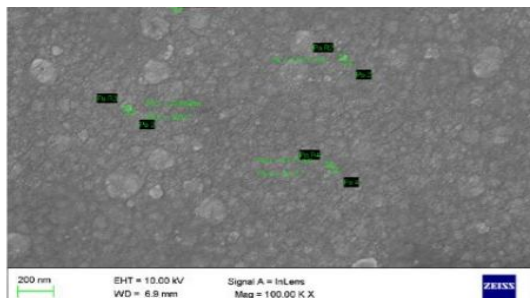


Fig. 4d FESEM of Al doped SnO₂ films deposited on glass substrates annealing at 600°C

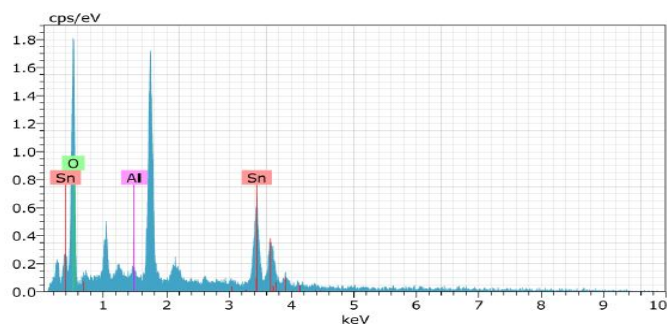


Fig. 5a EDAX of Al doped SnO₂ films deposited on glass substrates at 400°C

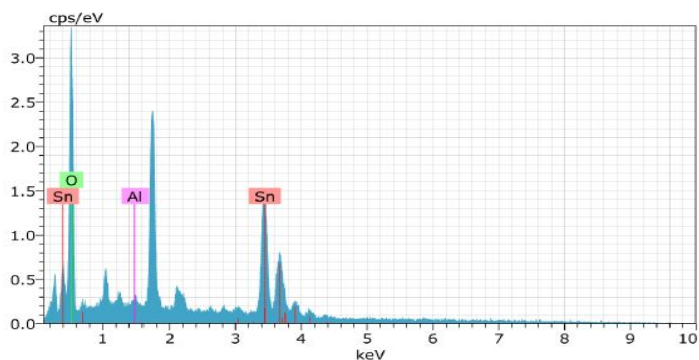


Fig. 5b EDAX of Al doped SnO₂ films deposited on glass substrates annealing at 500°C

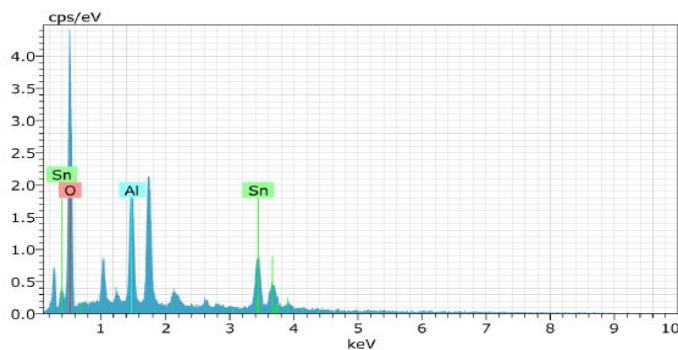


Fig. 5c EDAX of Al doped SnO₂ films deposited on glass substrates annealing at 600°C

D. AFM Analysis

The prepared thin films have been subjected to analyze the topography and nanostructure of the prepared Al doped SnO₂ thin films and the corresponding 3D AFM, Figure (6) showing the AFM image of Undoped SnO₂ thin film. The Figure 6a shows the homogeneously distributed crystallites. As seen from the figure 6b and 6c, the crystallites have grown from the inner towards the surface. This indicates that the growth of crystallites at 500°C has been faceted towards the top of the surface and looking like nano tips. There is no any presence of voids in the films. The average root mean square roughness (R_{ms}) values of the film (20nm) determined using the relation [13]. The estimated crystallite size is in consistent with the crystallite size measured from XRD data. A similar kind of topography was found in the literature [14]. Furthermore, increasing the annealing temperature caused the agglomeration.

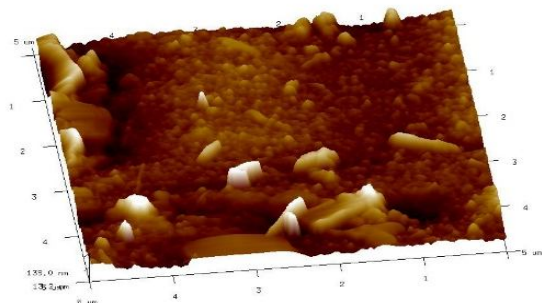


Fig. 6a AFM image of undoped SnO₂ films deposited on glass substrates at 400°C

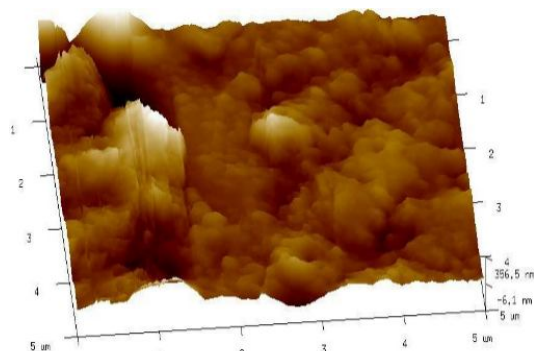


Fig. 6b AFM image of Al doped SnO₂ films deposited on glass substrates at 400°C

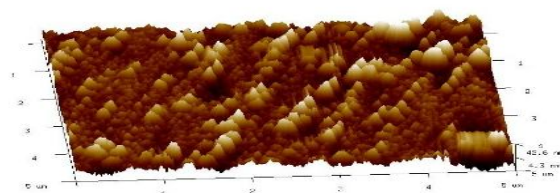


Fig. 6c AFM image of Al doped SnO₂ films deposited on glass substrates annealing at 500°C

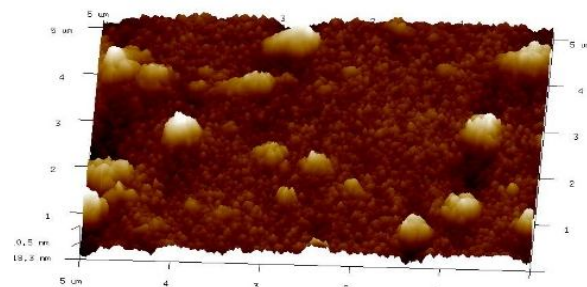


Fig. 6d AFM image of Al doped SnO₂ films deposited on glass substrates annealing at 600°C

IV. CONCLUSION

Aluminium doped SnO₂ nanocrystalline thin films have been successfully deposited onto glass substrate using simplified low coast homemade Spray pyrolysis technique with various of aluminum concentration (4%, 6%, 8%) and annealing at 500°C and 600°C. The effect of Al concentration and annealing to influence the changes of physical properties in Al: SnO₂ thin films, the presence of SnO₂ with tetragonal crystal structure were confirmed by XRD analysis and the average crystallite was estimated to be 45nm. The X-ray diffraction patterns confirmed the proper phase formation of material and EDAX studies of the films showed that the exact amount of Al in the films are less that taken in the solution. FESEM images demonstrated the presence of nano sized particles and substantiated the presence of Al, Sn and O elements. The prepared thin films are having good transparency (65%-85%) in the visible range, in the visible region and the transparency decreases with the increase of Al doping and annealing effect in the films. The direct allowed band gap of the films has been found to lie with the range of 2.6 to 3.6eV. More interesting the particle size, band gap decreasing with increasing Al concentration and annealing temperature. AFM image showed the dense and nanotips like topography for the thin films annealed at 500°C. High electrical conductivity and high carrier concentration that we obtained are quite promising for gas sensing devices and solar cell application.

REFERENCES

- [1] H.Kim, G.P.Kusho, C.B.Arnold, Z.H.Kafafi, A.Pique, W-doped SnO₂ and (W, Mn), (W,Ni) codoped SnO₂, Appl. Phys. Lett. 85 (2004) 464.
- [2] S.M.Rozati, S.Moradi, S.Golshahi, R.Martins, E.Fortunato, Electrical, structural and optical properties of fluorine-doped zinc oxide thin films: effect of the solution aging time, Thin Solid Films, 518 (2009) 1279.
- [3] S.M.Rozati, The effect of substrate temperature on the structure of tin oxide thin films obtained by spray pyrolysis method, Materials characterization, 57 (2006) 150.
- [4] S.M.Rozati, Effect of film thickness on the physical properties of ZnO: Al thin films deposited using a spray pyrolysis technique Canadian Journal of Physics, 86 (2008) 379.
- [5] I.S.Mulla, H.S.Soni, V.J.Rao, A.P.B.Sinha, Microstructural, optical and electrical investigations of Sb-SnO₂ thin films deposited by spray pyrolysis, J.Mater. Sci., 128, (2008),1442.
- [6] B.S.Chiou, S.T.Hsieh, W.F.Wu, Deposition of indium tin oxide films on acrylic substrates by radiofrequency magnetron sputtering, J.Am Ceram. Soc., 77(1994) 1740.
- [7] K. Karthik, V. Revathi, Tetiana Tatarchuk (2018) Microwave-assisted green synthesis of SnO₂ nanoparticles and their optical and photocatalytic properties, Molecular Crystals and Liquid Crystals, 671:1, 17-23, DOI: [10.1080/15421406.2018.1542080](https://doi.org/10.1080/15421406.2018.1542080)
- [8] Y.Takahashi, Y.Wade, The properties of antimony-doped tin oxide thin films by the sol-gel approach, J.Electrochem. Soc., 127 (1990) 267.
- [9] F.Moharrami, M.M.Bagheri-Mohagheghi, H.Azimi-Juybari, M.Shokooh-Saremi, Structural, electrical, optical, thermoelectrical and photoconductivity properties of the SnO₂-Al₂O₃ binary transparent conducting films deposited by the spray pyrolysis, Phy.Scr., 85 (6) (2012) 015703.
- [10] K. Pakiyaraj, V. Kirthika, K. Karthik (2019) Effect of annealing on the structural, morphological, optical and electrical properties of Al-Zn co-doped SnO₂ thin films, Materials Research Innovations, DOI: [10.1080/14328917.2019.1628498](https://doi.org/10.1080/14328917.2019.1628498)
- [11] A.Pohl, B.Dunn, Mesoporous indium tin oxide (ITO) films, Thin Solid Films, 515, (2006) 790.
- [12] Ganesh E Patil, Kajale D.D., Chavan D. N., Pawar N.K., Ahire P .T. , Shinde S. D., Gaikwad V. B. and Jain G. H., Bull. Synthesis, characterization and gas sensing performance of SnO₂ thin films prepared by spray pyrolysis Mater. Sci., 2011, 34(1), 1-9.
- [13] C.E. Benouis, M. Benhaliliba, Z. Mouffak, A. Avila-Garcia, A. Tiburcio-Silver, M. Ortega Lopez, R. Romano Trujillo, Y.S. Ocak, The low resistive and transparent Al-doped SnO₂ films: p-type conductivity, nanostructures and photoluminescence. Journal of Alloys and Compounds 603 (2014) 213–223.
- [14] E. Elangovan, K. Ramamurthi, Optoelectronic properties of spray deposited SnO₂: F thin films for window materials in solar cells. J. Optoelectron. Adv. Mater. 5 (2003) 45-54.
- [15] K.K. Purushothaman, M. Dhanasankar, G. Muralidharan, Effect of fluorine content on the morphological, structural, optical and electrical properties of nanostructured SnO₂ films Surf. Rev.Lett. 14 (2007) 1149-1152.
- [16] Zhenguo Ji, Lina Zhao, Zuopeng He, Qiang Zhou and Chen, Transparent p-type conducting indium-doped SnO₂ thin films deposited by spray pyrolysis, Mater. Lett., 2006, 60, 1387–1389.
- [17] Jain K., Pant R. P., Effect of Ni doping on thick film SnO₂ gas sensor, Sensors and Actuators B 113 (2006) 823–829.
- [18] K. Karthik, S. Pushpa, M. Madhukara Naik & M. Vinuth, Influence of Sn and Mn on structural, optical and magnetic properties of spray pyrolysed CdS thin films, Materials Research Innovations, 24:2 (2020) 82-86, DOI: [10.1080/14328917.2019.1597436](https://doi.org/10.1080/14328917.2019.1597436)
- [19] M.Benhaliliba, C.E Benouis, Y.S. Ocak, F.Yakuphanoglu Nanostructured Al doped SnO₂ films grown onto ito substrate via spray pyrolysis route Journal of nano and electronic physics vol.4 No 1, 01011 -1(spp)(2012).
- [20] Sk.F. Ahmed, P.K. Ghosh, S. Khan, M.K. Mitra, K.K.Chattopadhyay; Low-macroscopic field emission from nanocrystalline Al doped SnO₂ thin films synthesized by sol-gel technique, Appl.Phys.A86,139–143(2007).



10.22214/IJRASET



45.98



IMPACT FACTOR:
7.129



IMPACT FACTOR:
7.429



INTERNATIONAL JOURNAL FOR RESEARCH

IN APPLIED SCIENCE & ENGINEERING TECHNOLOGY

Call : 08813907089  (24*7 Support on Whatsapp)